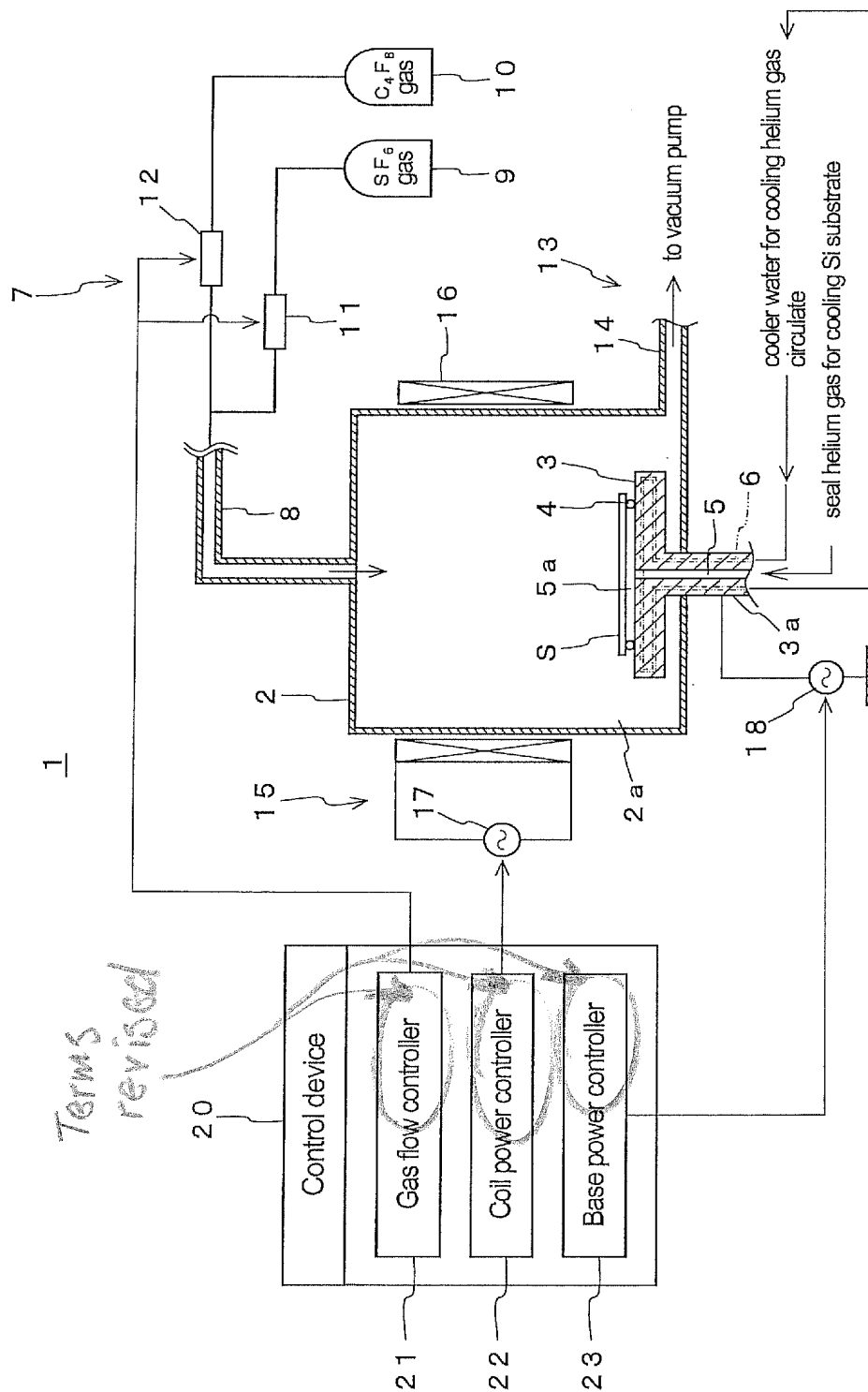


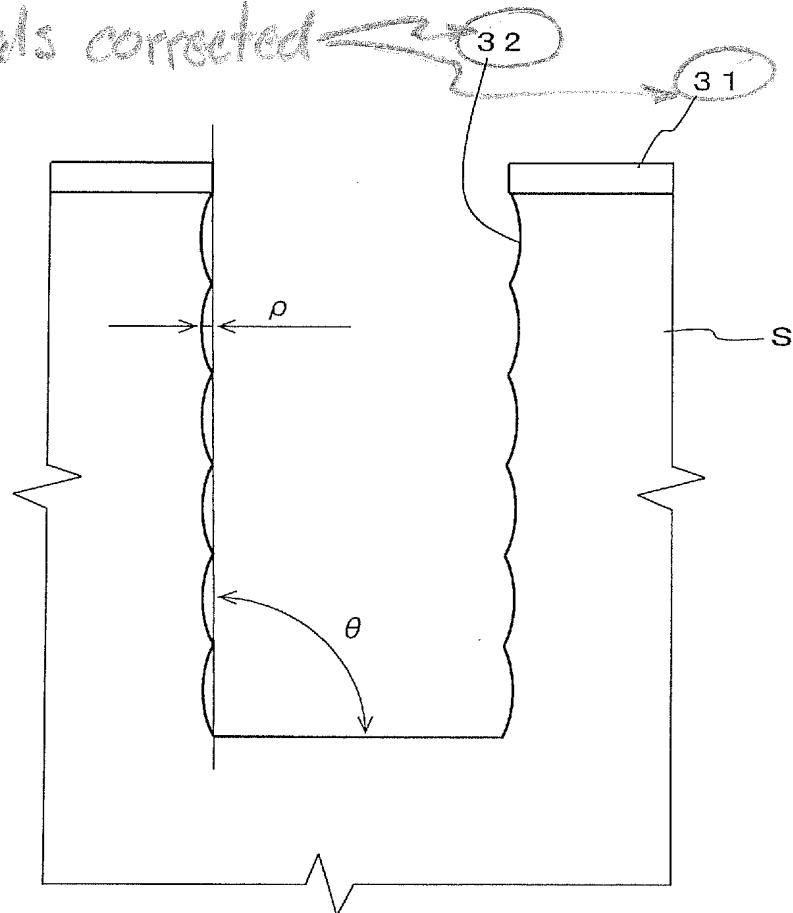
Fig. 1



Reference

numerals corrected

Fig. 3



*Fig. 4*

	Embodiment	Comparative Example
Etching rate ( $\mu\text{m}/\text{min}$ )	3.7	3.4
Mask selection ratio	140	104
Unevenness $\rho$ (nm)	160	250
Hole sidewall angle (degrees)	90.2	90.5

*Missing units added*